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# INTERNATIONAL STANDARD



Semiconductor devices – Micro-electromechanical devices – Part 40: Test methods of micro-electromechanical inertial shock switch threshold





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IEC Central Office 3, rue de Varembé CH-1211 Geneva 20 Switzerland

Tel.: +41 22 919 02 11

info@iec.ch www.iec.ch

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INTERNATIONAL ELECTROTECHNICAL COMMISSION

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### **CONTENTS**

| FOREWO     | RD   | 3   |
|------------|--|-----|
| 1 Scop     | e  | 5   |
| 2 Norm     | ative references   | 5   |
| 3 Term     | s and definitions  | 5   |
| 4 Esse     | ntial ratings and characteristics  | 7   |
| 4.1        | Recommended operating condition  | 7   |
| 4.2        | Characteristics  | 7   |
| 5 Test     | items and methods  | 7   |
| 5.1        | Switch type  | 7   |
| 5.2        | Static threshold   |     |
| 5.2.1      | Test method 1  |     |
| 5.2.2      |  |     |
| 5.3        | Dynamic threshold  |     |
| 5.3.1      | Test system  |     |
| 5.3.2      | Test procedure   | 11  |
| Ciaura 4   | The cohematic drawing of wiere electromach spicel in estimate about with | 6   |
| _          | The schematic drawing of micro-electromechanical inertia shock switch    |     |
|            | Test system 1 of static threshold  |     |
| •          | - Test system 2 of static threshold                                      |     |
|            | - Circuit diagram of switch  |     |
|            | - Static threshold of switch   |     |
| Figure 6 – | - Test system of dynamic threshold                                       | 10  |
|            |  |     |
|            | Characteristics of the switch threshold                                  |     |
| Table 2 –  | Test parameters of static threshold                                      | 8   |
| Table 3 –  | Test parameters of dynamic threshold                                     | 11  |
|            |  |     |
|            |  |     |
|            |  |     |
|            | $\mathcal{O}_{\mathcal{X}}$  |     |
|            |  |     |
|            |  |     |
|            |  |     |
|            | <b>O</b> ,   |     |
|            |  | A   |
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|            |  | 4   |
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### INTERNATIONAL ELECTROTECHNICAL COMMISSION

### SEMICONDUCTOR DEVICES – MICRO-ELECTROMECHANICAL DEVICES –

## Part 40: Test methods of micro-electromechanical inertial shock switch threshold

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IEC 62037-40 has been prepared by subcommittee 47F: Micro-electromechanical systems, of IEC technical committee 47: Semiconductor devices. It is an International Standard.

The text of this International Standard is based on the following documents:

| DRAFT        | Report on voting |
|--------------|------------------|
| 47F/384/FDIS | 47F/388/RVD      |

Full information on the voting for its approval can be found in the report on voting indicated in the above table.

The language used for the development of this International Standard is English.

This document was drafted in accordance with ISO/IEC Directives, Part 2, and developed in accordance with ISO/IEC Directives, Part 1 and ISO/IEC Directives, IEC Supplement, available at <a href="https://www.iec.ch/members\_experts/refdocs">www.iec.ch/members\_experts/refdocs</a>. The main document types developed by IEC are described in greater detail at <a href="https://www.iec.ch/standardsdev/publications">www.iec.ch/standardsdev/publications</a>.

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### SEMICONDUCTOR DEVICES – MICRO-ELECTROMECHANICAL DEVICES –

### Part 40: Test methods of micro-electromechanical inertial shock switch threshold

### 1 Scope

This part of IEC 62047 specifies the test conditions and methods of micro-electromechanical inertial shock switch threshold. This document applies to normally open micro-electromechanical inertial shock switch.

### 2 Normative references

There are no normative references in this document.

### 3 Terms and definitions

For the purposes of this document, the following terms and definitions apply.

ISO and IEC maintain terminological databases for use in standardization at the following addresses:

- IEC Electropedia: available at http://www.electropedia.org/
- ISO Online browsing platform: available at http://www.iso.org/obp

### 3.1

### micro-electromechanical shock inertial switch

device that is fabricated by micro-electromechanical system technology, and is closed or open via the contact or separation of fixed and movable electrode under or above a certain acceleration, also as known threshold switch, acceleration switch, or g switch